DOCKET NO: 242859US0DIV

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :

Hitoshi SAKAMOTO, et al. : ATTN: APPLICATION DIVISION

SERIAL NO: NEW APPLICATION :

FILED: HEREWITH :

FOR: HEXAGONAL BORON NITRIDE FILM WITH LOW DIELECTRIC CONSTANT, LAYER DIELECTRIC FILM AND METHOD OF PRODUCTION THEREOF, AND

PLASMA CVD APPARATUS

PRELIMINARY AMENDMENT

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

Prior to examination on the merits, please amend the above-identified application as follows:

Amendments to the Specification begins on page 2 of this paper.

Amendments to the Claims begins on page 3 of this paper.

Remarks begin on page 5 of this paper.